



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Inter Patent Application of : Docket: YOR920000344US1
Jack O. Chu et al. : Group Art Unit: 2813
Serial No.: 09/692,606 : Examiner: E. Kielin
Filed: October 19, 2000 : Date: October 26, 2001
For: Layer Transfer of Low Defect SiGe Using an Etch-back Process

Commissioner for Patents
Washington, D. C. 20231

CERTIFICATE OF MAILING UNDER 37 CFR 1.8(a)

I hereby certify that the attached correspondence comprising:

1. Acknowledgment Post Card;
2. Election/Restriction Under 37 CFR 1.141;
3. IDS and Form PTO 1449 with References AA - AE and AQ
are attached

is being deposited with the United States Postal Service as first
class mail in an envelope addressed to:

Commissioner for Patents
Washington, D. C. 20231

on October 26, 2001.

Michelle Parra

(Type or print name of person mailing paper)

Michelle Parra

(Signature of person mailing paper)

Attorney Docket No. YOR920000344US1

RECEIVED
OCT 27 2001
TO 4600 MAIL ROOM